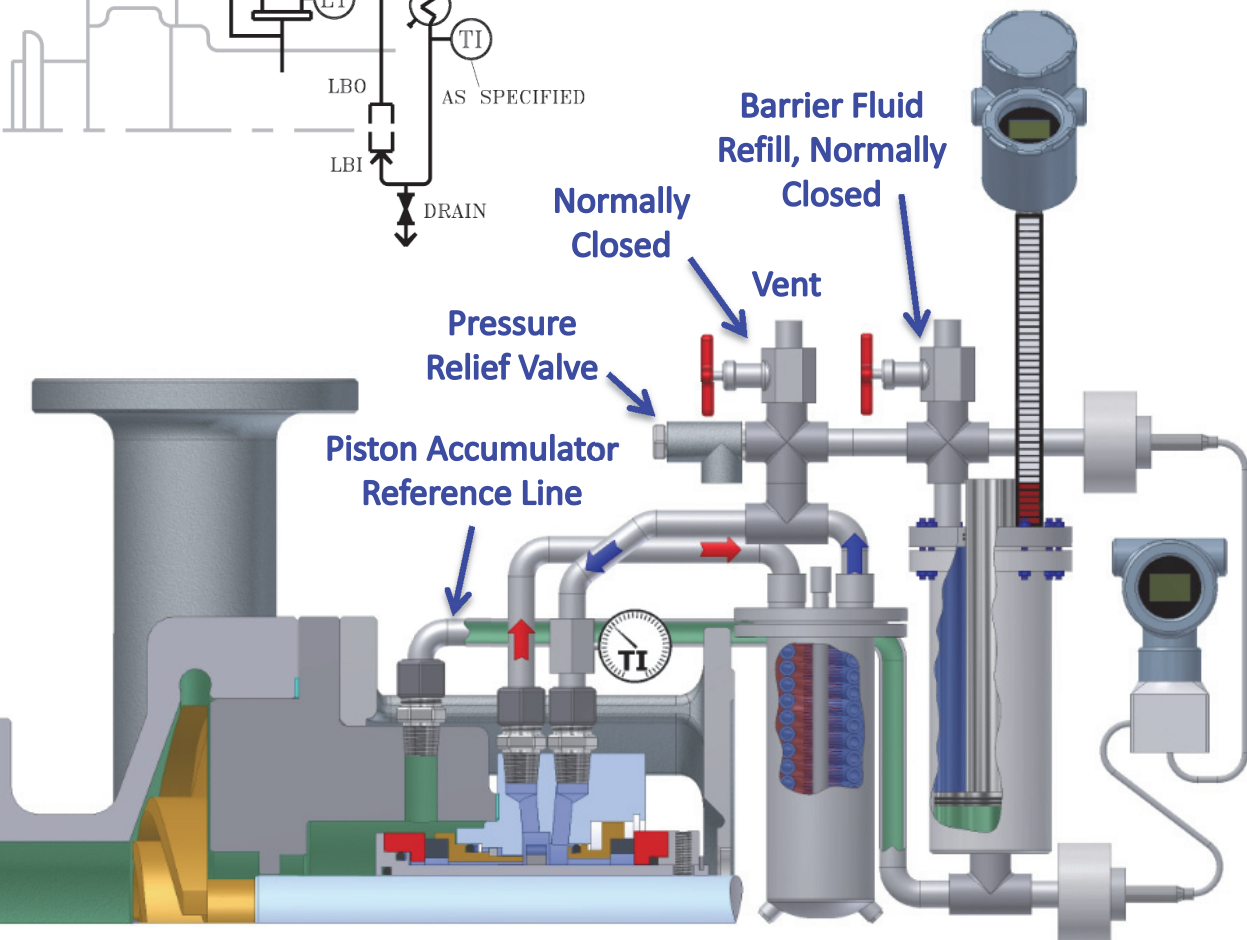
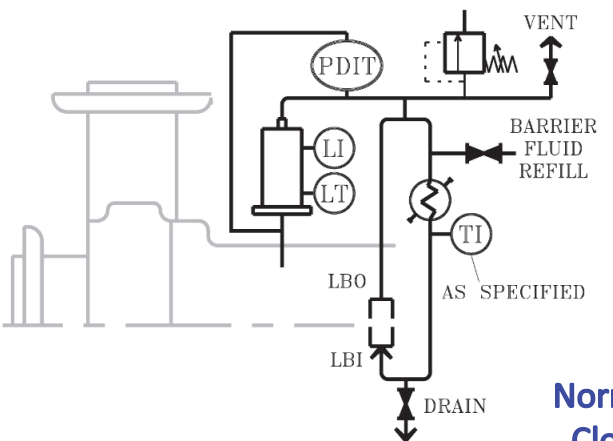


Plan 53C

Description: Plan 53C utilizes a reference line from the process in the seal chamber as a pressure source to a PISTON ACCUMULATOR. Provides a PRESSURIZED system greater than the process pressure being sealed, providing clean BARRIER fluid to an Arrangement 3 dual seal. Circulation provided by an internal pumping ring.



Objective: Same as Plan 53A, but will handle higher pressures and maintain a constant differential pressure above process pressure on the inner seal.

Advantages: Same as Plan 53B. Minimizes pressure reversals and maintains process seal stability.